

Attorney Docket: 061063-0356139
Client Reference:OSP-19398



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of
HOURAI ET AL.

Confirmation Number: 2722

Application No.: 10/587,039

Group Art Unit: 1792

Filed: July 24, 2006

Examiner: HITESHEW, FELISA C.

Title: SILICON WAFER, METHOD FOR MANUFACTURING THE SAME AND METHOD FOR
GROWING SILICON SINGLE CRYSTALS

COMMENTS ON EXAMINER'S STATEMENT OF REASONS FOR ALLOWANCE

Mail Stop Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the Notice of Allowability dated January 2, 2008, consideration of the following comments are respectfully requested.

In the Notice of Allowability, the Examiner has set forth "Reasons for Allowance." The Applicants respectfully traverse these Reasons. Specifically, it is submitted that the subject matter of the allowed claims are patentable for their respective recitations of claimed combinations as a whole, without any particular criticality or distinguishing feature being attributable to any one or more of such features, and without any narrowing interpretation being imposed on any of such features. The Applicants respectfully submit that the dependent claims are allowable not only for their dependence on the allowed independent claims, but also for the additional subject matter recited in each of those dependent claims.

Respectfully submitted,

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